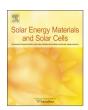
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# Inclusion of nanometer-sized silicon crystallites in *n*-layer for open circuit voltage enhancement in amorphous silicon solar cell



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### ABSTRACT

Material properties of hydrogenated silicon n-layer and their impact on amorphous silicon (a-Si:H) solar cell are studied. By optimizing deposition parameters, mixed-phase n-layer with nanometer-sized Si crystallites embedded in a-Si:H matrix can be obtained, which demonstrates higher conductivity, lower activation energy and wider bandgap. Incorporating the mixed-phase n-layer into a-Si:H cell can significantly improve the open circuit voltage ( $V_{oc}$ ) up to 0.95 V, which is approximately 50 mV or 100 mV higher than those cells with a-Si:H n-layer or microcrystalline silicon n-layer, respectively. The possible explanations of  $V_{oc}$  enhancement brought by the mixed-phase n-layer have also been discussed. Up to now, we have achieved an initial efficiency of 9.4% with high  $V_{oc}$  of 0.945 V, FF of 0.70 and  $J_{SC}$  of 14.2 mA/cm<sup>2</sup> with a-Si:H i-layer thickness of 300 nm and substrate temperature as high as 220 °C.

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### 1. Introduction

Over the past decades thin-film silicon-based multi-junction solar cell, consisting of amorphous silicon (a-Si:H), amorphous silicon germanium (a-SiGe:H) and microcrystalline silicon (µc-Si: H), has been widely investigated and regarded as the most potential candidate for the next-generation thin-film photovoltaic device [1-5]. Although advanced light trapping concepts and structures have been one of the recent hot-topics and have attracted extensive interest to improve the state-of-the-art device performance [6-9], optimizing the component solar cell itself in multi-junction solar cell, on the other hand, is still the chief issue to get high conversion efficiency. As for a-Si:H top cell, how to improve the open circuit voltage  $(V_{oc})$  is one of the most crucial issues [10-13]. Previous studies mainly focused on optimizing the absorption layers, p-type window layers and p/i interfaces. High hydrogen diluted intrinsic a-Si:H into the amorphous/microcrystalline phase transition region leads to  $V_{oc}$  higher than 1.0 V for pure a-Si:H solar cell [10,11]. Novel absorption layers including amorphous silicon carbide [12] and amorphous silicon oxide [13] are also reported. Much work has been performed on the *p*-type hydrogenated silicon alloy layers for the  $V_{oc}$  improvement, such as amorphous silicon carbide [14], amorphous silicon oxide [15], microcrystalline silicon carbide [16], nanocrystalline silicon [11] and nanocrystalline silicon oxide [17]. In addition, appropriate TCO/p or p/i interface treatment [18,19] and modifying the workfunction of indium tin oxide (ITO) front electrode [20] can also improve  $V_{oc}$ . On the other hand, there have been fewer studies on the effect of *n*-layers and even opposite role in determining the solar cell performance was presented [21,22]. Poissant et al. reported that although µc-Si:H n-layer has higher conductivity and lower activation energy, it also has narrow bandgap [21]. Replacing a-Si:H n-layer with  $\mu$ c-Si:H n-layer in p-i-n solar cell could not enhance the build-in potential and thus has little benefit for the  $V_{oc}$  improvement. On the contrary, Soderstrom et al. introduced an amorphous silicon carbide n-layer as a buffer layer at the n/i interface in n-i-p solar cell, which yields high  $V_{oc}$  and FF on both the flat and textured substrates [22]. Another issue to be mentioned is that the available  $V_{oc}$  for n-i-p a-Si:H cell is higher than that for p-i-n cell [10,11,17,18]. This phenomena can be mainly ascribed to the fact that in n-i-p multi-junction solar cell the a-Si:H top cell is deposited at last; thus it can be processed at lower substrate temperature  $(T_s)$ , resulting in wide bandgap for a-Si:H i-layer. However, a-Si:H top cell in p-i-n multi-junction solar cell is firstly deposited at higher  $T_s$ , which should be at least no less than  $T_s$  of a-SiGe:H or  $\mu$ c-Si:H cell. Therefore, how to get high  $V_{oc}$  in p-i-n a-Si:H top cell at higher  $T_s$  by only optimizing nlayer has been the topic of this paper. A wide bandgap and highly conductive Si:H layer with nanometer-sized Si crystallites (Si NCs) embedded in a-Si:H matrix was firstly fabricated. Then the opto-electronic and micro-structural properties and impact on the a-Si:H solar cell performance were investigated.

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### 2. Experimental details

Amorphous silicon based thin films and solar cells were deposited using a plasma enhanced chemical vapor deposition (PECVD) process in an ultrahigh-vacuum, multi-chamber, clustertool system. Mixtures of PH3, SiH4 and H2 were used for the fabrication of *n*-type Si:H layers deposited with silane concentration (SC=SiH<sub>4</sub>/[SiH<sub>4</sub>+H<sub>2</sub>]) from 2% to 9%, working pressure of 0.7 Torr, substrate temperature of 150 °C and RF (13.56 MHz) power of 10 W. Eagle2000 glass substrates were used for microstructural and opto-electronic characterization of Si:H lavers. Asahi SnO<sub>2</sub>:F substrates were used as the front electrodes for a-Si:H solar cells with configuration of glass/SiO<sub>2</sub>:F/p-proto-Si:H/ia-Si:H/n-Si:H/Al. The parallel conductivity was measured with coplanar electrode structure, while activation energy  $(E_a)$  was calculated from the temperature dependence of conductivity. The absorbance and reflectance spectra were measured with a Varian Cary 5000 UV-vis-NIR spectrophotometer. The optical bandgap  $(E_g)$  was calculated using Tauc's equation [23]

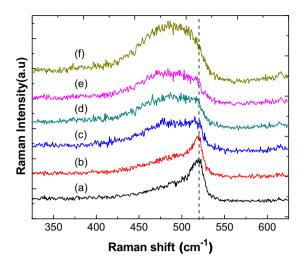
$$\alpha h \nu = A(h \nu - E_g)^n$$

where  $\alpha$  is the absorption coefficient, h is Plank's constant,  $\nu$  is the transmission frequency, and A is a constant. As for c-Si with indirect bandgap the exponent n value is 2, while it is 0.5 for a-Si:H with direct bandgap. For micro-structural characterization Raman scattering spectroscopy and high-resolution transmission electron microscopy (HR-TEM) were used. Raman scattering was measured on a glass substrate by a Renishaw RM2000 microscope with 488 nm excitation wavelength. HR-TEM was performed using Philips Tecnai  $G^2$ F20. Current-voltage characteristics and spectral response were measured with a Wacom solar simulator (WXS-156S-L2, AM1.5GMM) and a quantum efficiency system (QEX10, PV Measurement), respectively.

### 3. Results

## 3.1. Opto-electrical properties and micro-structural characterization of Si:H n-layers

By fine tuning the deposition parameters, especially the silane concentration ( $SC = SiH_4/[SiH_4 + H_2]$ ), a series of *n*-type Si:H layers were fabricated. Raman spectra of these layers shown in Fig. 1 could be deconvoluted into three Gaussian components: the crystalline part  $I_c$  (520 cm<sup>-1</sup>), amorphous part  $I_a$  (480 cm<sup>-1</sup>), and an intermediated interfacial part  $I_m$  (500 cm<sup>-1</sup>). The crystalline fraction ( $X_c$ ) was then calculated from  $X_c = (I_m + I_c)/(I_a + I_m + I_c)$  [24], and the average crystallite size (D) was deduced from the relationship between the Raman red-shift according to the bond polarizability model developed by Zi et al. [25]. Opto-electronic and micro-structural properties including bandgap ( $E_g$ ), conductivity ( $\sigma$ ), activation energy ( $E_a$ ), crystalline fraction and crystallite size are presented in Table 1. For the mixed-phase materials in Fig. 1 Tauc's equation is not strictly valid for the exact estimation of the band gap [26,27]. Here considering an approximation of indirect bandgap with n=2, Tauc's equation was just used to estimate an approximate band gap of such mixedphase materials [27]. For samples a and b obvious peaks at 520 cm<sup>-1</sup> as well as high  $X_c$  and larger crystallite size indicate a highly crystallized character. These two samples demonstrate higher conductivities and lower activation energies, but narrow bandgaps. A wide scattering band around 480 cm<sup>-1</sup> indicates a fully amorphous nature for sample f and it has highest activation energy, lowest conductivity and intermediate bandgap. For samples c, d and e Gaussian function deconvoluted Raman spectra reveal a mixed-phase structure including crystalline silicon and amorphous silicon. Although samples c, d and e have relative lower  $X_c$  (from 10% to 30%) than samples a and b, they



**Fig. 1.** Raman spectra of *n*-type Si:H layers with thickness of 30 nm on glass substrates.

**Table 1**Opto-electronic and micro-structural properties of different *n*-type Si:H layers with thickness of 30 nm on glass substrates.

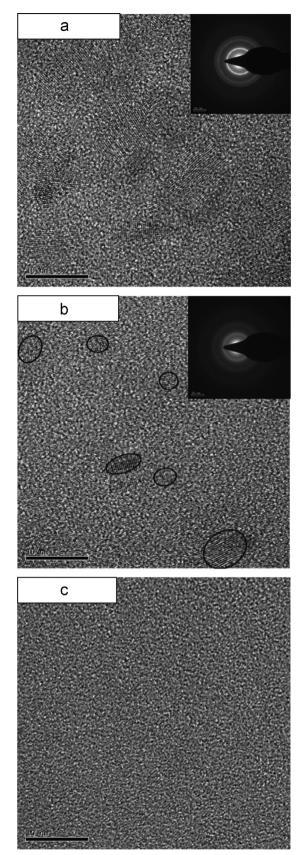
Sample no.	$E_a$ (meV)	$\sigma$ (S/cm)	$E_g$ (eV)	$X_c$ (%)	D (nm)
a	26	5.63	1.3	50	10
b	28	5.31	1.38	42	8
С	29	2.66	2.05	22	2.6
d	35	0.94	2.03	15	1.4
e	50	0.053	2.05	12	0.9
f	195	0.0042	1.83	0	0

demonstrate similar high conductivities and lower activation energies. In addition samples c, d and e have much wider bandgaps, while comparing the highly crystallized films (samples a and b) or the fully amorphous layer (sample f).

HR-TEM characterization was carried out to acquire more detailed microstructure of the above n-type Si:H layers. In order to simulate a more realistic structure a 5 nm thick intrinsic a-Si:H layer was first deposited on the copper TEM grids and then a 20 nm thick *n*-type Si:H layer was grown. This hybrid structure was designed to correspond to the standard i/n interface in p-i-na-Si:H solar cell. Samples with hybrid structures were named to be B, D and F, of which the 20 nm thick n-type Si:H layer was fabricated with identical deposition parameters as that of samples b, d and f in Table 1, respectively. Fig. 2(a) shows the HR-TEM image of sample B, in which Si-NCs with diameter around 10 nm or even larger could be found. The Si-NC density is high and these Si-NCs are connected to each other, which indicate a highly crystallized nature. As for sample D shown in Fig. 2(b) a mixedphase structure could be revealed with Si-NCs with smaller diameters from 2 nm to 5 nm embedded a-Si:H matrix. The Si-NC density is low and most of Si-NCs exist in isolated states, which show a strong quantum size-confinement effect. Selected area diffraction patterns for samples B and D, inset of Fig. 2(a) and (b), respectively, also indicate different crystalline fractions. For a-Si:H sample F no obvious crystal grain exists, as shown in Fig. 2 (c). The HR-TEM images in Fig. 2 provide direct evidence and further confirm the above-mentioned analysis based on the Raman spectra.

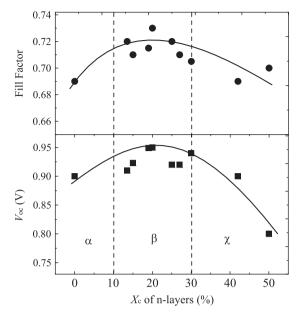
### 3.2. Effect on a-Si:H solar cell performance

Applying *n*-type Si:H films presented in Table 1 as *n*-layers, a series of a-Si:H solar cells have been fabricated with the same

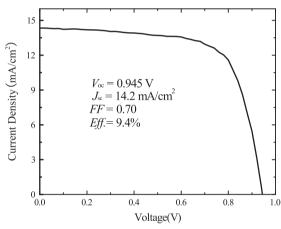


**Fig. 2.** High-resolution TEM images of sample B, D and F. Selected area diffraction patterns for sample B and D are also shown in the inset of (a) and (b), respectively.

p- and i-layers.  $V_{oc}$  and FF as a function of  $X_c$  of n-layers are plotted in Fig. 3, which can be divided into three regions named  $\alpha$ ,  $\beta$  and  $\chi$ . In region  $\alpha$   $X_c$  is in the range from 0% to 10%; amorphous structure



**Fig. 3.**  $V_{oc}$  and FF of a-Si:H solar cells as a function of  $X_c$  of n-layers.



**Fig. 4.** *J–V* curve of the best a-Si:H solar cell with mixed-phase nc-Si:H *n*-layer.

is dominated in these n-layers and  $V_{oc}$  is around 0.90 V. In region  $\beta$   $X_c$  of n-layers range from 10% to 30%, which correspond to mixed-phase nc-Si:H with nanometer-sized silicon crystallites embedded in a-Si:H matrix as that in Table 1 and Fig. 2. Both  $V_{oc}$  and FF can be significantly improved. For those solar cells with high  $X_c$  n-layers in region  $\chi$  significant  $V_{oc}$  decrease can be observed.

Typical  $V_{oc}$  of a-Si:H solar cells in region  $\beta$  with nc-Si:H n-layers are around 0.95 V, which is approximately 50 mV or 100 mV higher than those cells with a-Si:H n-layer or microcrystalline silicon n-layer, respectively. The best cell, we have achieved up to now, has  $V_{oc}$ =0.945 V (FF=0.70,  $J_{sc}$ =14.2 mA/cm² and  $\eta$ =9.4%) with 300 nm i-layer, as shown in Fig. 4. What should be mentioned here is that the substrate temperature for a-Si:H intrinsic layer is as high as 220 °C. Thus this high  $V_{oc}$  a-Si:H solar cell could be used as the top cell in multi-junction spectrum-splitting solar cell.

### 4. Discussion

Above results indicate that  $V_{oc}$  of a-Si:H solar cell can be remarkably improved by fine tuning the opto-electronic and micro-structural properties of Si:H n-layer into a mixed-phase

structure with Si-NCs embedded in a-Si:H matrix. The mixedphase nc-Si:H n-layer was deposited just above the phase transition region from amorphous silicon to microcrystalline silicon. It has not only lower activation energy, higher  $X_c$  and higher conductivity, but also wider bandgap. The conductivities presented in Table 1 are measured with coplanar electrode structures. where the carriers transport takes place in the lateral direction. However, in real solar cells, the carrier transport takes place in the vertical direction. It has been proved that for mixed-phase material the conductivity in the vertical direction is much higher than that in the lateral direction [28,29]. Thus the vertical conductivities for samples c, d and e will be much higher than those values presented in Table 1. Since a-Si:H solar cells in Fig. 3 were prepared with the same p- and i-layers, the higher conductivities and lower activation energies of nc-Si:H n-layers should lead to an increase in the built-in field in the devices, which is favorable for  $V_{oc}$  enhancement. In fact when high  $X_c$  n-layers are used  $V_{oc}$  of a-Si:H solar cells are even lower than those cells with fully a-Si:H *n*-layers, which is similar with the results in Ref. [21].

Compared with the results reported in the literature [22], the mixed-phase nc-Si:H n-layer also has relatively wider bandgap, which can diminish optical loss in the n-layer and the band alignment will be favorable for the  $V_{oc}$  improvement. The wider bandgap can be mainly ascribed to the quantum size-confinement effect [32,33] because of the isolated Si-NCs with diameters from 2 nm to 5 nm confirmed by HR-TEM measurement. On the other hand, the hydrogen-induced bandgap broadening is also reasonable and inevitable [34,35] due to the fact that most part of the mixed-phase silicon films is amorphous tissues. For the nc-Si:H n-layers, we suppose that they are distributed between the valence band and the conduction band, which creates a barrier for the holes and the electrons in the valence and conduction bands, respectively. The blocking barrier in the valence band helps to repel the holes from the defective interface area and reduces retro-diffusion of the holes in the *n*-layer. Hence, the nc-Si:H *n*layer enhances the collection of the charge carriers and leads to  $V_{oc}$ improvement.

### 5. Conclusions

We have developed a mixed-phase nc-Si:H n-layer and successfully incorporated it into a-Si:H based solar cell. For the mixed-phase nc-Si:H n-layer, its higher conductivity and lower activation energy help to increase in the built-in field, while the naturally formed graded buffer layer benefits for the carrier transport and collection. In addition the wide bandgap results in a blocking barrier to repel the holes from the defective interface area and then reduce retro-diffusion of the holes in the n-layer. Hence, the nc-Si:H n-layer significantly enhances  $V_{oc}$  of a-Si:H

solar cell approximately 50 mV or 100 mV higher than those cells with a-Si:H *n*-layer or microcrystalline silicon *n*-layer, respectively.

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